

NAME	TITLE	PROGR. REF.
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Wednesday, September 20th

Session 6A		Nanoscale Engineering and Fabrication 3	
Auditorium		Chair: Laura Heyderman, Vincent Derycke	
11:00-11:20	Christophe Yamahata	Towards wet anisotropic silicon etching of perfect pyramidal pits	6A-1
11:20-11:40	Livia Seemann	Nano-Xerography applied to nanoparticles and carbon nanotubes	6A-2
11:40-12:00	Rudeesun Songmuang	From rolled-up of Si microtubes to SiO _x /Si optical ring resonators	6A-3
12:00-12:20	Markus Fischer	Electron beam-induced direct-deposition of magnetic nanostructures	6A-4
12:20-12:40	James Liddle	Control of Lamellar Diblock Copolymers Through Patterned Surface Chemistry	6A-5
12:40-13:00	Ramona Mateiu	Batch fabrication of nanotubes suspended between microelectrodes	6A-6

Session 6B		Nanoimprint Lithography 2	
CIC1 Room		Chairs: Santos Merino, Douglas Resnick	
11:00-11:30	L. Montelius	Nanoimprint lithography for nanomechanics, electronics and life science applications	6B-1 INVITED
11:30-11:50	Yong Chen	Micro-aspiration assisted lithography	6B-2
11:50-12:10	Sergey Zaitsev	Coarse-grain method for modelling of stamp deformation in nanoimprint	6B-3
12:10-12:30	Yifang Chen	High density pattern fabricated in SU-8 by Nanoimprint and UV curing	6B-4
12:30-12:50	Tapio Mäkelä	Roll to roll nanoimprinting on inherently conducting polyaniline	6B-5
12:50-13:10	Javier G. Fernandez	Forced Soft Lithography (FSL) and its Application to the Fabrication of Structured Chitosan Biopolymer for Cell-Surface Interaction Experiments	6B-6

Session 6C		Maskless Lithography/Mask Technology	
A2+A3 Room		Chair: Serge Tedesco, Hiroyuki Ito	
11:00-11:20	Jingquan Lin	Actinic EUVL Mask Blank defects inspection by EUV photoemission electron microscope	6C-1
11:20-11:40	Hiroo Kinoshita	Observation of the internal defects of multilayer films	6C-2
11:40-12:10	J. Brugger	Nanostencil Lithography - Quick & Clean: Towards a reliable scalable nanopatterning method	6C-3 INVITED
12:10-12:30	Kun Liu	Towards a reliable scalable nanopatterning method	6C-4
12:30-12:50	Frank Thrum	CD control of direct versus complementary exposure for shaped beam writers and its correlation to the registration error	6C-5
12:50-13:10	Jan Pieter Kuijten	Process Impact from Mask Grid Variation	6C-6

Session 7A		Microsystems and their fabrication 3	
Auditorium		Chair: Regina Luttge, Zachary Davis	
15:00-15:20	Thomas Hantschel	Conductive diamond probes with electroplated holder chips	7A-1
15:20-15:40	Yong Chen	Characterization of Microfluidic Fuel Cell Based on Multiple Laminar Flow	7A-2
15:40-16:00	Daniel Witte	Lamellar Crystallization of Silicon for 3-dimensional Integration	7A-3
16:00-16:20	Anders Greve	Towards on-chip explosive detection using silicon cantilevers	7A-4
16:20-16:40	ling Wang	Micro-Nozzle Fabrication and Assembly for Nano-Emitter Electro spray	7A-5
16:40-17:00	Stefano Sardo	Fabrication of Apodized Bragg Gratings Structure for Tunable Filter	7A-6

Session 7B		Nanodevices 2	
CIC1 Room		Chair: Jose Maria De Teresa, Adrian Bachtold	
15:00-15:30	Robert Hartman	Future of nanoelectronics in Europe	7B-1 INVITED
15:30-15:50	Vincent Derycke	Carbon nanotubes self-assembly for electronic applications	7B-2
15:50-16:10	Tarek Lutz	Fabrication of a Nano-Scale NAND memory array based on a SONOS Fin-FET cell using e-beam lithography and Hydrogen-Silsesquioxane resist	7B-3
16:10-16:30	Filippo Romanato	Design and development of hybrid sol-gel films for direct patterning.	7B-4
16:30-16:50	Antonio Quattieri	Photonic crystal based organic random lasers	7B-5
16:50-17:10	Giuseppe Maruccio	Negative differential resistance and electron pathway in molecular tunnel-junctions based on individual Azurins	7B-6

Session 7C		Electron and Ion Beam Lithography 2	
A2+A3 Room		Chair: Ivan Kostic, Sergey Zaitsev	
15:00-15:30	A. Romano	Focused ion beam (FIB): a prototyping tool for micro and nanofabrication	7C-1 INVITED
15:30-15:50	Wolfgang Lang	Ion-beam modification of cuprate superconductors on a sub- μ m scale	7C-2
15:50-16:10	Stephen Thoms	Tilt-corrected stitching for electron beam lithography	7C-3
16:10-16:30	Yogesh Karade	Controlled sub-Micrometer Surface Morphologies by Thermal Relaxation of Locally Crosslinked Stretched Polymers Samples	7C-4
16:30-16:50	Liam O'Faolain	The effects of Lithography on Losses in Photonic Crystals	7C-5
16:50-17:10	Sumio Hosaka	Nano-dot arrays with a bit pitch and a track pitch of 25 nm	7C-6